



IFW

648.41957CX1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: TAMURA et al

Serial No.: 10/658,291

Filed: September 10, 2003

For: Vacuum Processing Device And Vacuum  
Processing Method

Art Unit: 1763

Examiner: K. Moore

**AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 19, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated October 19, 2005. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.